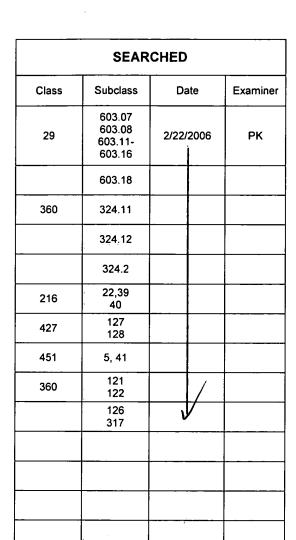
Search Notes

Application/Control No.	Applicant(s)/Patent under Reexamination	
10/655,942	HASEGAWA, NAOYA	
Examiner	Art Unit	
Paul D. Kim	3729	



INTERFERENCE SEARCHED				
Class	Subclass	Date	Examiner	
PGPub te see atta		10/11/2006	PK	

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	DATE	EXMR
Reviewed Parent Aplication 09/905,330 (US PAT. 6,751,073)`	2/22/2006	PK
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Updated Text Search EAST		
Updated Text Search EAST/PGPub	10/11/2006	PK